ORIGINAL RESEARCH ARTICLE

Microstructural and Mechanical Properties of Cr-Ni₃AI Alloy Films Synthesized by Magnetron Sputtering

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Cr-Ni3Al alloy films have been deposited on Si (100) substrate via DC magnetron sputtering. The effect of Cr enrichment on microstructure and mechanical properties has been studied. The evolution of phases, microstructure, surface topography and mechanical properties has been studied using GI-XRD, FE-SEM, AFM and quasi-static nanoindentation, respectively. Results revealed that the alloy films possessed a preferred orientation of (111) plane with a maximum hardness and Young's modulus of \sim 12.7 GPa and \sim 203 GPa for 0 W Cr-Ni3Al films which further decreased to \sim 7 GPa and 129 GPa, respectively, for 40 W Cr-Ni₃Al films. The reported values of hardness and Young's modulus are very high in the case of alloy Ni3Al-based coatings when compared with the literature. This study also imitates that with the increase in Cr concentration in the host $Ni₃Al$ matrix, the surface roughness increased as a result of the evolution of pores. However, hydrophobicity is observed to be increased with increase in Cr concentration in host Ni₃Al coatings with a maximum contact angle of 115.9° for 40 W Cr-Ni₃Al alloy film.

Keywords FE-SEM, hardness, hydrophobic property, magnetron sputtering, microstructure, Ni₃Al

1. Introduction

Over the past two decades, transition metal-based thin films are synthesized and characterized by several researchers for high-temperature applications (Ref [1](#page-8-0), [2\)](#page-8-0). These coatings have shown excellent mechanical and tribological properties at ambient and elevated temperatures (Ref [3-5](#page-8-0)). Moreover, some of the transition metal nitride coatings such as CrN, TiN, WN, etc., and Ni- and Ti-based coatings have shown enhanced properties in terms of corrosion and oxidation resistance along with microstructural stability (Ref [6](#page-8-0)-[8](#page-8-0)). Looking into the demand for high-temperature structural applications, researchers have fabricated, nickel and nickel superalloy-based coating because of their high thermal stability (Ref [9](#page-8-0), [10](#page-8-0)). In the past decade, the demand for enhanced surface properties and strength such as hardness and wear resistance in semiconductor, microelectronics and machining industries has led to the development of coatings with enhanced mechanical and tribological properties along with high-temperature stability (Ref $9-11$). In particular, Ni₃Al-based intermetallic compound coatings with excellent properties such as creep and fatigue resistance, thermal stability, high stiffness and high melting point make them a potential candidate for high-temperature applications such as gas turbine blades, jet engines, aerospace and nuclear industries (Ref [12-17](#page-8-0)). Moreover, doping of transition metals such as W, Cr, Pd and B in $Ni₃Al$ films in alloy or multilayer forms also alters their properties and mechanical behavior at ambient and high temperature (Ref [18-](#page-8-0) 20). Alloying Ni₃Al intermetallic with Fe has increased mechanical properties whereas it has resulted in improving high-temperature strength when doped with zirconium (Zr) because of solid solution hardening (Ref [21\)](#page-8-0). It has been reported that boron doped in Ni3Al films, extensively occupies the Al sites, or the element which is a substitute for both Al and Ni is ductilized by boron resulting in increasing the overall ductility of the film (Ref 22). While synthesizing Ni₃Al-based coatings, phase formation and microstructure have a great impact on mechanical and tribological properties. It has been reported that with an increase in crystallite size, the hardness generally decreases and vice versa following the Hall–Petch,

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but in some cases, inverse Hall–Petch results have been observed (Ref [19,](#page-8-0) [23,](#page-8-0) [24](#page-8-0)). In the literature, it has been found that, despite increasing the crystallite and grain size of the film, mechanical and tribological properties have increased. This has been perceived because of the formation of ordered $L1₂$ preferred orientation of Ni₃Al films which contributes to increasing the hardness of the film (Ref [25](#page-8-0)).

There are several factors affecting the properties and microstructure of Ni₃Al films while depositing via magnetron sputtering. Sputtering process parameters such as sputtering pressure and substrate temperature influence grain growth, refinement and rearrangement which results in altering the properties of the film (Ref [26\)](#page-8-0). Moreover, heat treatment postdeposition also contributes to varying the properties of the Ni₃Al films.

Swygenhoven et al. (Ref 27) deposited Ni₃Al alloy and Ni/ Ni3Al multilayer films on Si substrate via DC magnetron sputtering. To study the hardness of the film, alloy Ni₃Al film was deposited with 400-nm thickness whereas the multilayer films were deposited with two different layer thicknesses of Ni₃Al/Ni as 2.5 nm and 5 nm. Researchers found that the alloy films showed a maximum hardness of \sim 13 GPa whereas the Ni/Ni₃Al with an individual layer thickness of 5 nm showed a hardness of \sim 12 GPa, and the film with an individual layer thickness of 2.5 nm showed a hardness of 11.8 GPa. Thin films deposited in the form of alloy and multilayers have shown enhanced hardness as compared to that of the bulk $Ni₃Al$ (\sim 9.5) GPa).

Ng et al. (Ref 8) deposited Ni₃Al films onto the Ni substrate using the multitarget system by putting the Ni and Al sheets glued together on a thin circular metal sheet and with casted alloy Ni3Al targets also via sputtering. They found that the sputtering yield of Ni was more as compared to Al. Accordingly, they claimed that to find the composition in the ratio of 75:25 at.% (Ni:Al), the multitarget should have an area of 23Ni:13Al whereas the alloy target should have the composition of Ni-32at.%Al. The results of microhardness revealed that

the as-deposited film and the film annealed at 300 $^{\circ}$ C showed almost the same hardness whereas the maximum hardness was shown by the film annealed at 700° C. They also found a continuous fall in hardness as a result of an increase in indentation depth.

Xing et al. (Ref 26) in their research to synthesize Ni₃Al and $Ni₃A/Cr$ multilayer films found that the hardness $Ni₃A1 Cr$ decreased as compared to single-layered $Ni₃Al$ films whereas Young's modulus increased. They also found that both the single-layered and multilayered films were able to prevent the substrate from being drastically oxidized at an elevated temperature of 900 $^{\circ}$ C whereas the toughness of multilayer films was increased.

Zhang et al. (Ref 19) found that the hardness of Ni₃Al films doped with ultra-thin Cr layers in multilayer forms increased with an increase in Cr content and annealing temperature. In their further research while synthesizing Ni/Ni₃Al multilayer films, with different individual layer thicknesses of Ni and Ni₃Al (layer thickness $h < 100$ and $h = 160$), they found that the $Ni/Ni₃Al$ film showed the preferred orientation of (111) texture. It is seen that with decreasing individual layer thickness, there appears a peak broadening in the XRD spectrum reflecting a decrease in the crystallite size of the film. Results of nanoindentation showed that the hardness of the annealed films was low as compared to as-deposited Ni/ Ni3Al films which further decreased with an increase in the individual layer thickness of Ni and Ni3Al (Ref [23\)](#page-8-0). In our previous research, alloy Ni₃Al films were deposited on Si substrate via DC magnetron sputtering (Ref [28\)](#page-8-0). The result of nanoindentation revealed that the alloy Ni₃Al film possessed a hardness of \sim 13 GPa as reported by Swygenhoven et al. (Ref [27](#page-8-0)) while enriching the film further with Ni via co-sputtering, it was observed that the hardness and Young's modulus of the film decreased with the evolution of cracks and pores.

Several research groups have studied the properties and behavior of Ni₃Al-based films at ambient and high temperatures. However, very limited research is available in the literature in the case of alloy deposition particularly using dopants in alloy form. The present work reports on the effect of Cr in Ni₃Al films in alloy form on its microstructural and mechanical properties for their application in microelectronic devices, molding industries and structural application in aerospace industries.

2. Experimental Procedure

2.1 Synthesis of Film

Cr-Ni3Al alloy films were deposited on Si (100) substrates via co-sputtering. The films were deposited at a substrate temperature of 400 $^{\circ}$ C in a custom-designed vacuum chamber. Alloy target of $Ni₃Al$ (2-inch diameter and 5-mm thickness; 99.99% purity) and Cr target (2-inch diameter and 5-mm thickness; 99.99% purity) was placed in DC-powered sputtering guns placed at 120° apart from each other at the bottom of the chamber. Si substrates were initially cleaned with acetone and then dried in the air before clamping to the substrate holder. The substrate holder was rotated at a speed of 10 rpm to ensure the homogeneous deposition of the film over the substrates. The sputtering chamber was evacuated at a base pressure of $3 \times$ 10^{-6} mbar in order to eliminate the impurities and contaminants. Argon (99.999% purity) as a processed gas (30 sccm) was inserted in the chamber, and the pressure during sputter deposition was kept constant at 3×10^{-2} mbar during deposition. DC power of 250 W was supplied to the $Ni₃Al$ target to deposit $Ni₃Al film (namely, 0 W Cr)$. To vary the concentration of Cr in Ni₃Al films, the power supply to Cr target was varied from 10 W to 40 W in steps of 10 W to deposit Cr-Ni3Al alloy films, namely, 10 W Cr; 20 W Cr; 30 W Cr and 40 W Cr. Prior to deposition, pre-sputtering of 5 minutes was done on both the targets to remove the impurity from the surface of the targets whereas the actual sputtering was done for a duration of 1 hour. Other than the DC power to the Cr target, all the sputtering parameters were kept constant during all depositions.

Fig. 1 GIXRD spectra of Ni₃Al and Cr-Ni₃Al alloy films

2.2 Characterization of Phase and Microstructure

Grazing angle x-ray diffraction (Empyrean PANalytical) was used to detect the phases of Ni₃Al-based films using $CuK\alpha = 0.154$ Å at ambient temperature. The microstructure and surface topography of the films were characterized by FE-SEM (Zeiss Gemini) and atomic force microscopy (NaioAFM, Nanosurf, Switzerland). The elemental composition of Cr in Ni₃Al films was characterized using energy-dispersive spectroscopy equipped with FE-SEM.

2.3 Nanoindentation and Contact Angle Measurements

Quasi-static nanoindentation (nano-DMA, Hysitron Inc., Minneapolis, USA, TI-900) was performed to investigate the hardness and Young's modulus of Ni₃Al and Cr-Ni₃Al coatings. The depth-control nanoindentation test was performed at ambient temperature with a strain rate of 0.05^{-1} calibrated at a Poisson's ratio of 0.25. The average depth of penetration during the nanoindentation test was 100 nm and kept constant throughout the set of experiments. The mechanical property in terms of hardness and Young's modulus was calculated using Oliver and Pharr's technique by the inbuilt software in the nanoindentation setup. A total of 20 indents were made using a Berkovich diamond tip to calculate the average value of hardness and Young's modulus.

In order to measure the contact angle to study the hydrophobic properties of the films, a drop shape analysis experiment (DSA 100, Krüss GmbH, Germany) was performed. Distilled water droplets of 0.5 μ l were dropped on 10 different places of the deposited surface in order to calculate the average contact angle between the deposited surface and water droplets. The contact angle and the profile of the water droplets dropped over the deposited surface were calculated using the camera and backlight installed in the setup. The experiment was conducted at ambient temperature in static conditions.

3. Results and Discussion

3.1 Identification of Phase and Microstructure

XRD patterns of Cr-Ni₃Al alloy coatings with different concentrations of Cr in alloy form are shown in Fig. 1. It can be seen that the Ni₃Al film (0 W Cr) displays a preferred (111) orientation at 44.13° followed by low-intensity diffraction peaks of (200) and (220) planes at 51.3° and 75.2° of facecentered cubic structure, respectively (Ref [27-29](#page-8-0)). These diffraction peaks are also in accord with the standard intermetallic $L1_2$ diffraction peaks of Ni₃Al. XRD patterns of Cr-Ni₃Al films do not display any evidential diffraction peaks of Cr. This is attributed to the substitution of Ni by Cr atoms from the host Ni3Al lattice structure which causes the strain to induce in the film (Ref [22,](#page-8-0) [26](#page-8-0)). When Cr replaces Ni atoms of the host Ni3Al lattice structure, it causes the formation of tensile residual stress. The value of strain in Ni₃Al and Cr-Ni₃Al calculated from the prominent peak of XRD spectra using Eq 1 (Ref [30](#page-8-0)) is shown in Table[1](#page-3-0).

$$
\epsilon = \beta/4 \tan \theta \tag{Eq 1}
$$

where ε is microstrain, β is FWHM and θ is Bragg's angle.

The microstructure of Cr-Ni₃Al is characterized using FE-SEM as shown in Fig. 2. From the figure, it is seen that 0 W Cr-

Table 1 Calculated parameters of $Cr-Ni₃Al$ coatings as a function of Cr enrichment

Fig. 2 FE-SEM images of Cr-Ni3Al films (a) 0 W Cr, (b) 10 W Cr, (c) 20 W Cr, (d) 30 W Cr and (e) 40 W Cr

Ni3Al film exhibits fine, equisized and densely packed consolidated grains reflecting smooth and homogeneous microstructure. Furthermore, in 10 W Cr-Ni₃Al film, there is the evolution of coarser grains and pores on the morphology of the deposited film resulting in inhomogeneous microstructure. A simultaneous increase in microcracks and pores is observed with a further increase in the Cr content (up to 40 W Cr) in the host Ni₃Al film. This could be the result of the agglomeration of crystallites resulting in grain growth which later contributes to deteriorating the arrangements of grains and grain bound-

aries. ImageJ software is used to calculate the percentage of porosity in the film using the SEM images of the Cr-Ni₃Al films (Ref [31\)](#page-8-0). Results revealed that 0 W Cr-Ni₃Al films exhibited minimum percentage of pores $(10.3%)$ whereas 40 W Cr-Ni₃Al films showed the maximum percentage of pores (14%) in the film as shown in Table 1.

Furthermore, the grain size of the deposited films has also been calculated using ImageJ software. For this purpose, we have used the FE-SEM images. The distribution of grain size in Ni_{[3](#page-4-0)}Al and Cr-Ni₃Al films is shown in Fig. 3. From the figure, it

Fig. 3 Distribution of grains in $Cr-Ni₃Al$ coatings

size of 91 \pm 2.5 and 195 \pm 5.0 nm have been calculated for 10 W Cr-Ni_3 Al and 40 W Cr-Ni_3 Al film, respectively (Ref 31).

distribution of smaller grains with an average grain size of 91 ± 2.5 nm. With further increase in Cr content in the film, the distribution of grains becomes inhomogeneous as a result of grain coarsening which simultaneously continues up to 40 W Cr enrichment in the film. The minimum and maximum grain

is observed that 10 W Cr-Ni₃Al reflects the homogeneous

The surface topography of deposited alloy films has been studied and explored using atomic force microscopy. The cantilever probe of AFM scanned an area of $10 \times 10 \mu m^2$ to reveal information about the surface asperities of the deposited

Fig. 4 Three-dimensional and 2D AFM images of Cr-Ni3Al films (a) 0 W Cr, (b) 10 W Cr, (c) 20 W Cr, (d) 30 W Cr and (e) 40 W Cr

films. However, to calculate the average surface roughness (rms) of the film, the area of 50 \times 50 μ m² was scanned at 10 different spots. Figure 4 shows the 2D and 3D AFM images of Cr-Ni3Al films. From the figure, it can be observed that the

Ni3Al film with 0 W Cr exhibits closely packed high frequency of fine, thin and sharp hill-type structured nano-asperities of less intensity. A subsequent and continuous increase in a domelike broad asperities with distorted structures has been observed

Fig. 5 Hardness and Young's modulus of Cr-Ni₃Al films as a function of power to Cr target

Fig. 6 Hall–Petch relationship of Ni₃Al and Cr-Ni₃Al films

in Cr-Ni3Al coatings as a result of increase in Cr content. This led to an increase in surface roughness and also an increase in void fraction. The surface roughness (rms) of the deposited films calculated using AFM is reported in Table [1](#page-3-0). The minimum and maximum surface roughness of 7.50 ± 0.23 nm and 14.80 ± 0.71 nm have been observed for 0 W Cr-Ni₃Al and 40 W Cr-Ni₃Al films, respectively.

3.2 Contact Angle Measurements

Contact angle measurements have been performed and examined on a drop shape analyzer at ambient temperature. In order to study the hydrophobic property of the film, the contact angle has been measured between water droplets and the deposited surface with different concentrations of Cr in steady state as shown in Table [1.](#page-3-0) Results showed that the contact angle increases simultaneously with increase in Cr concentration in Ni3Al film. This could be the result of the subsequent increase in the surface roughness of the film with Cr enrichment as indexed in Table [1.](#page-3-0) With the increase in surface roughness of

Fig. 7 Load versus displacement graph of $Cr-Ni₃Al$ films

the film, there is increase in void fraction too. These available voids between the nano-asperities of the surface help in trapping the air which decreases the surface contact area between water and deposited films and thus increases the hydrophobic property of the film (wettability is decreased). It has been reported in the literature that increase in surface roughness increases the hydrophobic property of the film up to a limit (Ref [28](#page-8-0)). From the results of AFM, it can be seen that there is a sudden increase in surface roughness of 10 W Cr- $Ni₃Al films$ (7.50 nm-9.42 nm) which lead to a dramatic rise in water contact angle too. However, the marginal difference in surface roughness of 20 W Cr-Ni₃Al and 30 W Cr-Ni₃Al (11.91 nm-12.63 nm) has reflected a small degree of variation in contact angle. The lowest and highest contact angle of 75.5 and 115.9° have been found for 0 W Cr-Ni₃Al and 40 W Cr-Ni₃Al coatings, respectively. The work shows the efficient method to deposit the Ni₃Al films with Cr enrichment which convert the hydrophilic films to hydrophobic in nature for their application in microelectronic devices which facilitates heat dissipation.

3.3 Mechanical Properties

Mechanical properties of Cr-Ni₃Al have been investigated in terms of nano-hardness and Young's modulus. Depth-control quasi-static nanoindentation was used to evaluate the results of mechanical properties at ambient temperature. The results of nano-hardness and Young's modulus are plotted in Fig. 5. It can be observed that the hardness of the film decreased with increase in power supply to Cr target. This is because of the increase in Cr content in host $Ni₃Al$ film (as a result of the increase in power supply to Cr target) which led to an increase in the overall film thickness which further contributes to agglomeration of crystallites resulting in grain size enlargement. Furthermore, the larger grains contributed to the generation of large volumes of microcracks and pores (Table [1\)](#page-3-0) which led to the degradation of the microstructure of the film. Figure 6 shows the summarized result of hardness versus inverse square root of the grain size. From the figure, it can be observed that the hardness of the film is directly proportional to the inverse square root of grain size obeying the classical Hall– Petch relation. This is evident that the hardness of the film decreases with increase in grain size following the dislocation

Fig. 8 H/E and H^3/E^2 ratios of Ni₃Al coatings enriched with Cr content

pileup model. The films with smaller grain sizes consisted of large volumes of grain boundaries which resist the dislocation movement across the boundaries and are piled up near the grain boundaries which led to the enhancement in hardness (Ref [30,](#page-8-0) [32](#page-8-0)). Moreover, the value of R^2 is very close to 1 ($R^2 = 0.974$) which suggests that the regression line fits the data well resulting in a high value of H–P coefficient [slope = 184.04615 \pm 17.34491 GPa (nm^{1/2})]. The literature shows that the H–P coefficient of the nanomaterials is in the range of 40-144 with hardness in the range of 10 GPa-17 GPa (Ref [33-35](#page-8-0)). It is also reported that the hardness of the film increases with increase in H–P coefficient. In our case, however, the value of the H–P coefficient is higher, but the presence of cracks and pores in the films degrades the microstructure resulting in the evolution of hardness in the range of \sim 7-12.7 GPa.

It has also been reported that the variation in hardness as a function of grain size is compensated by the chemical ordering of FCC Ni3Al film (formation of thermodynamic equilibrium $Ni₃Al L1₂ phase)$ (Ref [25\)](#page-8-0) which says that with the increase in grain size, the hardness of the film increases if the ordered equilibrium L_1 , $Ni₃Al$ phase is formed in nanocrystalline films (Ref 23 , 25 , 36). In our case, the XRD spectrum of Ni₃Al film (0 W Cr) showed a prominent peak of Ni₃Al (111) at 44.13° which is also in accord with the standard intermetallic L_1 ₂ structure contributing in increasing the hardness of the film. However, the presence of the pores in $Cr-Ni₃Al$ films contributes in lowering the hardness of the alloy $Cr-Ni₃Al$ films. The evolution in Young's modulus also shows the same trend as reflected by the nano-hardness curve. Figure [7](#page-6-0) reflects the load versus depth curve as a function of Cr enrichment in Ni₃Al alloy films. A maximum load (P_{max}) of 2.8 mN is recorded during depth-control nanoindentations. From the figure, it can be observed that the deposited films showed both elastic and plastic deformations during loading whereas only elastic deformation has been observed during unloading (Ref [35](#page-8-0)). Moreover, 0 W and 10 W Cr-Ni3Al samples reflected almost the same permanent deformation depth of \sim 38 nm and \sim 40 nm, respectively, whereas 20 W Cr-Ni₃Al samples showed a permanent deformation depth of \sim 46 nm. The maximum permanent deformation depth of 60 nm is observed for both 30 W Cr-Ni₃Al and 40 W Cr-Ni₃Al films. This shows that 0 W Cr and 10 W Cr possess a better rate of elastic

recovery as compared to 20 W Cr, 30 W Cr and 40 W Cr films. The highest value of H/E and H^3/E^2 calculated from the results of nanoindentation (Fig. 8) is evident that 10 W Cr-Ni₃Al film imitates better resistance to plastic deformation whereas the 40 W Cr-Ni3Al reflects the maximum plastic deformation. This also reveals that the toughness of the $Ni₃Al$ coatings decreased with increase in Cr concentration (Ref [35,](#page-8-0) [37,](#page-8-0) [38\)](#page-8-0). Xing et al. (2013) (Ref [26\)](#page-8-0) also found similar results in terms of a decrease in hardness when they synthesized $Cr/Ni₃Al$ multilayer films. It has been reported that the $Ni₃Al films$ in multilayer forms when enriched with nickel have reflected a hardness in the range of \sim 4.5-8 GPa (Ref [24](#page-8-0), [39](#page-8-0)[-41\)](#page-9-0). Some studies based on doped Ni3Al with transition metals in multilayer forms followed by heat treatment have shown an increase in the hardness beyond 8 GPa (Ref [19](#page-8-0), [23](#page-8-0), [25\)](#page-8-0). Researchers have found that the hardness of Ni3Al-based multilayer thin films is mostly influenced by the microstructure, layer thickness, indentation depth and annealing at high temperatures (Ref [42,](#page-9-0) [43](#page-9-0)). However, very limited research has been reported in the literature on the case of doped Ni₃Al films in alloy forms. In our case, the maximum and minimum hardness of 12.7 \pm 0.8 GPa and 7.0 \pm 0.5 GPa have been observed for 0 W Cr-Ni₃Al and 40 W Cr-Ni₃Al alloy films whereas the maximum and minimum Young's modulus of 203 ± 15 GPa and 129 \pm 5.6 GPa have been observed for 0 W $Cr-Ni₃Al$ and 40 W $Cr-Ni₃Al$, respectively. The Ni₃Al-based coatings with high hardness reported in this work can be used in scratch-resistant connectors, slider and other components of electronic devices and molding dies.

4. Conclusion

 $Ni₃Al$ and Cr-Ni₃Al alloy films with variations in Cr concentration have been synthesized via DC magnetron sputtering. The microstructure, phase and mechanical properties of the deposited films have been investigated. XRD patterns of Ni₃Al and Cr-Ni₃Al alloy films have reflected a preferred orientation of the (111) plane followed by lowintensity peak of (200) and (220). However, no evidence of Cr in diffraction peak of Cr-Ni₃Al films has been observed upon enriching the host Ni₃Al film with Cr. The increase in sputtering power to the Cr target resulted in enriching the Cr content in the films which further led to the evolution of porosity resulting in degradation of the surface roughness. The maximum percentage of pores (14%) have been observed in 40 W Cr-Ni₃Al films with highest surface roughness of 14.80 ± 0.71 nm. 0 W Cr-Ni₃Al alloy film has shown the highest value of hardness $(12.7 \pm 0.8 \text{ GPa})$ and Young's modulus (203 \pm 15 GPa) that decrease with increase in Cr content. Contact angle measurements reveal that Cr-Ni₃Al films are hydrophilic in nature but converts to hydrophobic with increase in Cr content in the samples. The maximum contact angle of 115.9° is observed for 40 W Cr-Ni₃Al films.

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